

MNC 2015 (November 10-13, Toyama International Conference Center, Toyama, Japan) Schedule

Tuesday, November 10

Room A (203 and 204, 2F)
13:10-16:45 MNC 2015 Technical Seminar in Japanese
Lobby (3F)
17:10-19:10 Get Together Party

Technical Seminar in Japanese Registration Desk
November 10, 12:30 - 16:00 (1F Lobby)

Conference Registration Desk
November 10, 16:30 - 18:30 (1F Lobby)
November 11, 8:30 - 18:00 (1F Lobby)
November 12, 8:30 - 18:30 (1F Lobby)
November 13, 8:30 - 16:30 (1F Lobby)

Wednesday, November 11

Room P (3F)			
11P-1: Opening & Plenary Session 9:30-12:10			
Lunch			
Room A (203 and 204, 2F)	Room B (202, 2F)	Room C (201, 2F)	Room D (Special Conf. Room, 2F)
11A-2: 13:30-15:35 Symposium A: Symposium on "Big Data" for Advanced Patterning I	11B-2: 13:30-15:20 Organic Nanomaterials	11C-2: 13:30-15:00 Carbon Nanotube	11D-2: 13:30-15:00 BioMEMS, Lab on a Chip I
	11B-2 Author's Interview: 15:20-15:30	11C-2 Author's Interview: 15:00-15:10	
Lobby (2F)			
Coffee Break			
11A-3: 15:55-17:25 Resist and Directed Self-Assembly	11B-3: 15:55-17:25 Nanofabrication I	11C-3: 15:35-17:05 Inorganic Nanomaterials I	11D-3: 15:25-17:15 BioMEMS, Lab on a Chip II
11A-3 Author's Interview: 17:25-17:35	11B-3 Author's Interview: 17:25-17:35	11C-3 Author's Interview: 17:05-17:15	11D-2,3 Author's Interview: 17:15-17:25
Room A (203 and 204, 2F)			
17:35-19:00 Happy Hour			

Thursday, November 12

Room A (203 and 204, 2F)	Room B (202, 2F)	Room C (201, 2F)	Room D (Special Conf. Room, 2F)
12A-4: 9:00-10:30 Symposium C: Next Generation Lab on a Chip I	12B-4: 9:00-10:10 Nanodevices I	12C-4: 9:00-10:30 Symposium B: Two Dimensional Nanomaterials I	12D-4: 9:00-10:30 Nanoimprint, Nanoprint and Rising Lithography I
Lobby (2F)			
Coffee Break			
12A-5: 10:45-12:15 Symposium C: Next Generation Lab on a Chip II	12B-5: 10:25-11:45 Nanodevices II	12C-5: 10:45-11:55 Symposium B: Two Dimensional Nanomaterials II	12D-5: 10:45-11:45 Nanoimprint, Nanoprint and Rising Lithography II
	12B-4,5 Author's Interview: 11:45-11:55	12C-4,5 Author's Interview: 11:55-12:05	12D-4,5 Author's Interview: 11:45-11:55
Lunch			
12A-6: 13:30-15:10 Electron and Ion Beam Technologies	12B-6: 13:30-15:00 Nanofabrication II	12C-6: 13:30-15:10 Inorganic Nanomaterials II	12D-6: 13:30-15:30 NanoTool
12A-6 Author's Interview: 15:10-15:20	12B-6 Author's Interview: 15:00-15:10	12C-6 Author's Interview: 15:10-15:20	12D-6 Author's Interview: 15:30-15:40
Lobby (2F)			
Coffee Break			
Lobby (2F and 3F)			
12P-7: 16:00-18:00 Poster Session I Electron and Ion Beam Technologies, Resist and Directed Self-Assembly, Nanocarbons, Nanodevices, Nanofabrication, Inorganic Nanomaterials, Organic Nanomaterials, NanoTool, Nanoimprint, Nanoprint and Rising Lithography, BioMEMS, Lab on a Chip and Microsystem Technology and MEMS			
ANA Crowne Plaza Toyama (Room Ohtori 3F)			
18:15-20:15 Banquet			

Friday, November 13

Room A (203 and 204, 2F)	Room B (202, 2F)	Room C (201, 2F)	Room D (Special Conf. Room, 2F)
13A-8: 9:00-10:00 Symposium A: Symposium on "Big Data" for Advanced Patterning II	13B-8: 9:00-10:10 Nanofabrication III	13C-8: 9:00-10:30 Nanocarbon Application I	13D-8: 9:00-10:30 Microsystem Technology and MEMS I
Lobby (2F)			
Coffee Break			
Room A (203 and 204, 2F)	Room B (202, 2F)	Room C (201, 2F)	Room D (Special Conf. Room, 2F)
13A-9: 10:15-11:45 Symposium A: Symposium on "Big Data" for Advanced Patterning III	13B-9: 10:25-11:45 Nanofabrication IV	13C-9: 10:45-11:55 Nanocarbon Application II	13D-9: 10:45-11:45 Microsystem Technology and MEMS II
	13B-8,9 Author's Interview: 11:45-11:55	13C-8,9 Author's Interview: 11:55-12:05	13D-8,9 Author's Interview: 11:45-11:55
Lunch			
13A-10: 13:30-14:40 Advanced Photolithography	13B-10: 13:30-14:50 Nanodevices III	13C-10: 13:30-14:50 Nanocarbon Application III	13D-10: 13:30-14:30 Microsystem Technology and MEMS III
13A-10 Author's Interview: 14:40-14:50	13B-10 Author's Interview: 14:50-15:00	13C-10 Author's Interview: 14:50-15:00	13D-10 Author's Interview: 14:30-14:40
Lobby (2F and 3F)			
13P-11: 15:20-17:20 Poster Session II Advanced Photolithography, Resist and Directed Self-Assembly, Nanocarbons, Nanodevices, Nanofabrication, Inorganic Nanomaterials, NanoTool, Nanoimprint, Nanoprint and Rising Lithography, BioMEMS, Lab on a Chip and Microsystem Technology and MEMS			